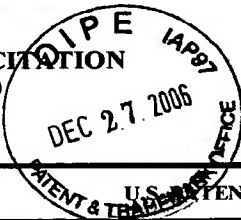


Receipt date: 12/27/2006

INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)



Docket Number (Optional)

F06-436-US

Application Number

10569838/569838:1792

Applicant(s)

Mineo HIRAMATSU, et al.

Filing Date

February 24, 2006

Group Art Unit

Unknown

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

U.S. PATENT APPLICATION PUBLICATIONS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

FOREIGN PATENT DOCUMENTS

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
							YES	NO
		2001-081570	03/27/2001	JAPAN			ABS	
		11-067490	03/09/1999	JAPAN			ABS	
		2003-173980	06/20/2003	JAPAN			ABS	

OTHER DOCUMENTS

(Including Author, Title, Date, Pertinent Pages, Etc.)

		Office Action of Japanese Patent Application No. 2005-513488, with partial English translation
		"Formation of Vertically Aligned Carbon Nanotubes by Dual-RF-Plasma Chemical Vapor Disposition", by Takashi HIRAO, et al.

EXAMINER

/Mandy Louie/

DATE CONSIDERED

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